



**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**  
Form PTO-1449 (Modified)  
(Use several sheets if necessary)

**COMPLETE IF KNOWN**

Application Number	10/636,021
Confirmation Number	1017
Filing Date	6 August 2003
First Named Inventor	David A. Palsulich
Group Art Unit	2812
Examiner Name	(To Be Assigned)
Attorney Docket No.	106298727US

Sheet 1 of 2

**U.S. PATENT DOCUMENTS**

Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
EC		4,839,005		Katsumoto et al.	06/13/1989	
		5,196,353		Sandhu et al.	03/23/1993	
		5,621,847		Tillotson et al.	04/15/1997	
		5,658,183		Sandhu et al.	08/19/1997	
		5,762,537		Sandhu et al.	06/09/1998	
		5,807,165		Uzoh et al.	09/15/1998	
		5,842,909		Sandhu et al.	12/01/1998	
		5,893,754		Robinson et al.	04/13/1999	
		5,957,750		Brunelli	09/28/1999	
		5,980,363		Meikle et al.	11/09/1999	
		5,981,396		Robinson et al.	11/09/1999	
		6,066,030		Uzoh	05/23/2000	
		6,117,781		Lukanc et al.	09/12/2000	
		6,143,155		Adams et al.	11/07/2000	
		6,176,992	B1	Talieh	01/23/2001	
		6,187,681	B1	Moore	02/13/2001	
		6,218,309	B1	Miller et al.	04/17/2001	
		6,287,974	B1	Miller	09/11/2001	
		6,312,558	B2	Moore	11/06/2001	
		6,368,190	B1	Easter et al.	04/09/2002	
		6,375,548	B1	Andreas	04/23/2002	
		6,451,714	B2	Powell	09/17/2002	
		6,455,370	B1	Lane	09/24/2002	
		2002/0160606	A1	Siefering et al	10/31/2002	
		2003/0060030	A1	Lee et al.	03/27/2003	
		2003/0057106	A1	Shen et al.	03/27/2003	

EXAMINER

DATE CONSIDERED

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4/27/05

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				Application Number	10/636,021
				Confirmation Number	1017
				Filing Date	8 August 2003
				First Named Inventor	David A. Palsulich
				Group Art Unit	2812
Examiner Name	(To Be Assigned)				
Attorney Docket No.	108298727US				

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No.	Foreign Patent or Application			Name of Patentee or Applicant of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T
		Office	NUMBER	Kind Code (if known)				
EC  ↓	**	WO	90/04045	A1	Advantage Production Technology, Inc.	04/19/1990		
	**	WO	00/05753	A1	Applied Materials, Inc.	02/03/2000		
	**	WO	02/23109	A1	Applied Materials, Inc.	03/21/2002		
	**	WO	03/021642	A2	Applied Materials, Inc.	03/13/2003		

OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.			T
EC	**	Solvay S.A., "Electricity and Electronics - Semiconductors," 2 pages, January 20, 2003, < <a href="http://www.solvaysolexis.com/Semiconductors.htm">http://www.solvaysolexis.com/Semiconductors.htm</a> >.			
↓	**	Solvay Solexis, Inc., "Hyflon MFA and PFA Design Guide," 15 pages, December 13, 2002, < <a href="http://www.solvaysolexis.com/pdf/HYFLON_GUIDE.pdf">http://www.solvaysolexis.com/pdf/HYFLON_GUIDE.pdf</a> >.			
↓	**	Walker, P. and W.H. Tarn, CRC Handbook of Metal Etchants, 1991, CRC Press LLC, pp. 914-915.			

EXAMINER	DATE CONSIDERED
<i>Eric Chen</i>	4/27/05